

ELECTRONIC INFORMATION DISCLOSURE STATEMENT

Electronic Version v18

Stylesheet Version v18.0

Title of Invention

HIGH-PRESSURE PROCESSING CHAMBER FOR A
SEMICONDUCTOR WAFER

Application Number : 10/680783



Confirmation Number: 5859

First Named Applicant: William Jones

Attorney Docket Number:

Art Unit:

Examiner:

Search string: (5306350 or 5772783 or 5850747 or 5858107 or 5943721 or 5946945 or 5970554 or 6070440 or 6264753 or 6612317 or 6736149 or 6764552 or 6805801 or 6851148 or 6874513).pn

Certification: This Information Disclosure Statement was submitted under the following conditions, which satisfies the requirement under 37 CFR 1.97(e). The filer certified:

That no item of information contained in the information disclosure statement was cited in a communication from a foreign patent office in a counterpart foreign application, and, to the knowledge of the person signing the certification after making reasonable inquiry, no item of information contained in the information disclosure statement was known to any individual designated in 37 CFR 1.56(c) more than three months prior to the filing of the information disclosure statement.

US Patent Documents

Note: Applicant is not required to submit a paper copy of cited US Patent Documents

init	Cite.No.	Patent No.	Date	Patentee	Kind	Class	Subclass
	1	5306350	1994-04-26	Hoy et al.			
	2	5772783	1998-06-30	Stucker			
	3	5850747	1998-12-22	Roberts et al.			
	4	5858107	1999-01-12	Chao et al.			
	5	5943721	1999-08-31	Lerette et al.			
	6	5946945	1999-09-07	Kegler et al.			
	7	5970554	1999-10-26	Shore et al.			
	8	6070440	2000-06-06	Malchow et al.			
	9	6264753	2001-07-24	Chao et al.			
	10	6612317	2003-09-02	Costantini et al.			
	11	6736149	2004-05-18	Biberger et al.	B2		
	12	6764552	2004-07-20	Joyce et al.	B1		
	13	6805801	2004-10-19	Humayun et al.	B1		
	14	6851148	2005-02-08	Preston et al.	B2		

	15	6874513	2005-04-05	Yamagata et al.	B2		
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Signature

Examiner Name	Date